

Electronic Acknowledgement Receipt

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Application Number:	10665982
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Title of Invention:	Process for etching silicon wafers
First Named Inventor:	Henry F. Erk
Customer Number:	321
Filer:	Andrew C. Wegman/Valarie McLaurin
Filer Authorized By:	Andrew C. Wegman
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages
1		LTPTO.PDF	121093	yes	15

	Multipart Description		
	Doc Desc	Start	End
	Amendment - After Non-Final Rejection	1	1
Applicant Arguments/Remarks Made in an Amendment		2	15
Warnings:			
Information:			
Total Files Size (in bytes):		121093	
<p>This Acknowledgement Receipt evidences receipt on the noted date by the USPTO of the indicated documents, characterized by the applicant, and including page counts, where applicable. It serves as evidence of receipt similar to a Post Card, as described in MPEP 503.</p> <p>New Applications Under 35 U.S.C. 111 If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.</p> <p>National Stage of an International Application under 35 U.S.C. 371 If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.</p>			